Electronic Version
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Claims

[c1] A method for the manufacture of microstructures (18) in substrates (24), comprising using a combination of photolithographic mask technology and micro contact printing.

[c2] A method for the manufacture of microstructures in substrates, comprising the steps of
a) providing a process mask (10);
b) creating soft stamps (16) from a master comprising a microstructure (18);
c) attaching said soft stamps (16) to said mask (10);
d) stamping a desired pattern into a resist layer (26) provided on a substrate (24) to be processed; and
e) curing said pattern with UV light

[c3] The method according to claim 2, wherein said mask (10) comprises a plating compensation area.

[c4] The method according to claim 3, wherein said plating compensation area is covered with a metallic layer (12).

[c5] The method according to claim 4, wherein said metal is chromium.

[c6] The method according to claim 2, wherein said microstructure (18) is mechanically stabilized by greater holding blocks (20, 22) attached to said microstructure (18).

[c7] The method according to claim 2, characterized in that said microstructure (18) has an aspect ratio in the area of 1:5 to 1:20.

[c8] A P2 structure for a magnetic recording head, said structure being manufactured according to the method of claim 2.